

**Notice of References Cited**

Application/Control No.

10/563,651

Applicant(s)/Patent Under  
Reexamination  
VAN DAM ET AL.

Examiner

John P. Zimmermann

Art Unit

2861

Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-5,757,015 A	05-1998	Takemoto et al.	250/491.1
*	B	US-2003/0142167 A1	07-2003	Nakamura et al.	347/37
*	C	US-2003/0179252 A1	09-2003	Nakamura, Shinichi	347/2
*	D	US-2003/0189604 A1	10-2003	Bae et al.	347/2
*	E	US-4,941,745 A	07-1990	Sugiyama, Shuji	356/401
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP 2003121635 A	04-2003	JP	Sakurada, Kazuaki	B41J 002/01
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	JP 2003-121635 A - DERWENT Publication
	V	JP 2003-121635 A - Machine Translation, <a href="http://www4.ipdl.inpit.go.jp">http://www4.ipdl.inpit.go.jp</a>
	W	JP 08-086913 - Machine Translation, <a href="http://www4.ipdl.inpit.go.jp">http://www4.ipdl.inpit.go.jp</a>
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.